



# IIT Bombay Nanofabrication Facility

## Tool Name: Sputter (ATC 2200)

### Training and Usage Policy

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#### Contamination policy:

1. Targets used in Orion cannot be used in ATC 2200 sputter as Orion is Cu and Au contaminated. Separate (dedicated) targets are to be used for ATC.
2. Resist coated samples are not allowed (Yet to be tested)
3. Au/ Cu coated samples are not allowed.

#### Training Policy for ATC 2200 Sputter

Policy: Training is open for all CEN users now as the DST project is over.

Shadow training: To do a process or be along with another user and go through the operating procedure, if the user hasn't used the system for more than 3 months (90 days).

**Allowed break: 180 days**, after which you will have to give a re-authorization test.

#### Training Procedure: (02-08-2021 onwards)

We have started a new training procedure, which aims at reducing the time and effort to train user without compromising the performance and its efficacy.

1. Send a request using the link below:

[http://www.cen.iitb.ac.in/equipment\\_usage/index.php](http://www.cen.iitb.ac.in/equipment_usage/index.php)

2. Once approved, go through the SOP. This SOP contains all the information about the tool, operating procedure, reference video links and overall checklist.
3. After going through the SOP, you will be eligible for a supervised hands-on.
4. After the hands-on, there will a quiz next day.
5. Final test will be taken by the system owner or the operator.

### **Violation Policy:**

1. System mishandling would lead to DAC and re-authorization by undergoing through the training procedure again.
2. Standard sample mishandling and using non-allowed materials would lead to debarring from using the system for 7 days.